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APPLICATION NO.	FI	ILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/006,704	1	12/10/2001	Shane J. Trapp	M4065.0369/P369-A 3229	
24998	7590	02/13/2006		EXAMINER	
		IRO MORIN & OS	UMEZ ERONINI, LYNETTE T		
2101 L Street, NW Washington, DC 20037				ART UNIT	PAPER NUMBER
				1765	

DATE MAILED: 02/13/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

			f°				
		Application No.	Applicant(s)				
Office Action Summary		10/006,704	TRAPP, SHANE J.				
		Examiner	Art Unit				
		Lynette T. Umez-Eronini	1765				
Period for	- The MAILING DATE of this communication app Reply	pears on the cover sheet with the	correspondence address				
WHICI - Extens after S - If NO - Failure Any re	DRTENED STATUTORY PERIOD FOR REPLY HEVER IS LONGER, FROM THE MAILING DOISIONS of time may be available under the provisions of 37 CFR 1.1 (SIX (6) MONTHS from the mailing date of this communication. Period for reply is specified above, the maximum statutory period to to reply within the set or extended period for reply will, by statute the ply received by the Office later than three months after the mailing of patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION (36(a). In no event, however, may a reply be twill apply and will expire SIX (6) MONTHS from (6), cause the application to become ABANDON	N. imely filed m the mailing date of this communication. ED (35 U.S.C. § 133).				
Status							
1)🛛 🗆	Responsive to communication(s) filed on 17 N	lovember 2005.					
2a)⊠ ¹	This action is FINAL . 2b) This action is non-final.						
3)□ :	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is						
•	closed in accordance with the practice under E	Ex parte Quayle, 1935 C.D. 11, 4	453 O.G. 213.				
Dispositio	on of Claims						
4)🛛	Claim(s) 17,26-29,31 and 77 is/are pending in the application.						
4	4a) Of the above claim(s) is/are withdrawn from consideration.						
5) 🗌 🖟	Claim(s) is/are allowed. Claim(s) <u>17,26-29,31 and 77</u> is/are rejected.						
6)⊠ (
·	Claim(s) is/are objected to.						
8) 🗌 (Claim(s) are subject to restriction and/o	or election requirement.	·				
Application	on Papers						
9)⊠ Т	The specification is objected to by the Examine	er.					
10)⊠ Т	The drawing(s) filed on <u>10 December 2001</u> is/a	are: a)⊠ accepted or b)□ obje	cted to by the Examiner.				
	Applicant may not request that any objection to the	drawing(s) be held in abeyance. Se	ee 37 CFR 1.85(a).				
	Replacement drawing sheet(s) including the correct	tion is required if the drawing(s) is o	bjected to. See 37 CFR 1.121(d).				
11) 🔲 🏻	The oath or declaration is objected to by the Ex	xaminer. Note the attached Offic	e Action or form PTO-152.				
Priority u	nder 35 U.S.C. § 119						
	Acknowledgment is made of a claim for foreign 〗All b)囗 Some * c)囗 None of:	priority under 35 U.S.C. § 119(a)-(d) or (f).				
	1. Certified copies of the priority documents have been received.						
:	2. Certified copies of the priority documents have been received in Application No						
;	3. Copies of the certified copies of the prio	rity documents have been receiv	ved in this National Stage				
	application from the International Burea	` ' ' '					
* Se	ee the attached detailed Office action for a list	of the certified copies not receive	ved.				
Attachment((s)						
1) Notice	e of References Cited (PTO-892)	4) Interview Summar					
	e of Draftsperson's Patent Drawing Review (PTO-948)	Paper No(s)/Mail I					
. —	nation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) No(s)/Mail Date	6) Other:	Tatorit repplication (FTO-102)				

DETAILED ACTION

Specification

1. The amendment filed 11/17/2005 is objected to under 35 U.S.C. 132(a) because it introduces new matter into the disclosure. 35 U.S.C. 132(a) states that no amendment shall introduce new matter into the disclosure of the invention. The added material which is not supported by the original disclosure is as follows:

Although the Specification discloses, "Other etchant gases which may be introduced into the reaction chamber together with the foregoing ammonia and fluorocarbon(s) can include oxygen, nitrogen and other compounds which are generally available in plasma etching" (page 10, lines 11-13), the Specification fails to exclude other compounds, which are generally available in plasma etching from the plasma etching composition that consists essentially of:

at least two fluorocarbons, and ammonia, wherein said at least two fluorocarbons, and said ammonia form a reactive mixture, as recited in claim 25;

CF₄, at least one other fluorocarbon and NH₃ wherein said CF₄, said at least one other fluorocarbon, and said NH₃ form a reactive mixture, as recited in claim 71; and

wherein at least one other fluorocarbon, at least one additional gas selected from the group consisting of oxygen and nitrogen, and ammonia, wherein said at least on fluorocarbon, said at least one additional gas, and said ammonia form a reactive mixture, as recited in claim 77.

Applicant is required to cancel the new matter in the reply to this Office Action.

Claim Rejections - 35 USC § 112

2. The following is a quotation of the first paragraph of 35 U.S.C. 112:

The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.

3. Claims 26-29, and 31 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the written description requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to reasonably convey to one skilled in the relevant art that the inventor(s), at the time the application was filed, had possession of the claimed invention.

In claim 26, "A plasma etching composition consisting essentially of: at least two fluorocarbons and ammonia. . . form a reactive mixture;"

In claims 71, ""A plasma etching composition consisting essentially of: CF₄, at least one other fluorocarbon and NH₃... form a reactive mixture; and

In claims 77, "A plasma etching composition consisting essentially of: at least one additional gas selected from the group consisting of oxygen and nitrogen, and ammonia, form a reactive mixture" is not supported by the Specification, which fails to exclude other compounds, which are generally available in plasma etching (Specification, page 10, lines 11-13) from the plasma etching composition.

"A consisting essentially of" claim occupies a middle ground between closed claims that are written in a consisting of format and fully open claims that are drafted in a comprising' format." PPG Industries v. Guardian Industries, 156 F.3d 1351, 1354, 48 USPQ2d 1351, 1353-54 (Fed. Cir. 1998). When an applicant contends that additional

steps or materials in the prior art are excluded by the recitation of "consisting essentially of," applicant has the burden of showing that the introduction of additional steps or components would materially change the characteristics of applicant's invention.

Rejections - 35 USC § 102

4. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 5. Claims 26-29 and 31 are rejected under 35 U.S.C. 102(e) as being anticipated by Loewenstein (US 4,857,140).

Loewenstein teaches, a gas mixture that contains a fluorine source and a source of hydrogen, wherein the fluorine source is taken from the group of CF_4 , F_2 , SF_6 and C_2F_6 singly or in combination and the hydrogen source is taken from the group of CH_4 , H_2 , NH_3 , hydrocarbon or any molecule with and abstractable hydrogen atom (claims 1-6 and 8, and 9), which reads on,

A plasma etching composition consisting essentially of at least two fluorocarbons and ammonia. Since Loewenstein discloses the same gaseous composition as claimed by applicants, and gas molecules collide and in constant motion, then using Loewenstein's composition in the same manner as claimed by applicants would inherently result wherein said at least one fluorocarbon and ammonia form a reactive mixture, as recited **in claim 26**; and further read on and result in,

A plasma etching composition consisting essentially of at least one other fluorocarbon and NH₃, wherein said CF₄, said at least one fluorocarbon and said NH₃ form a reactive mixture, as recited in claim 71.

The above also reads on,

wherein said at least two fluorocarbons are selected from the group consisting of fluorocarbons, as in claim 27;

wherein said at least two fluorocarbons are selected from the group consisting of C_4F_8 , C_4F_6 , C_5F_8 , CF_4 , C_2F_6 , CHF_3 , and CH_2F_2 , in claim 28; and

wherein said at least two fluorocarbons are selected from the group consisting of CF₄, CHF₃, and CH₂F₂, in claims 29 and 31.

Loewenstein also discloses a gas taken from the group of CF_4 , F_2 , SF_6 and C_2F_6 and an inert carrier taken from the group of helium, argon or nitrogen; and a source of hydrogen taken from the group of CH_4 , H_2 , NH_3 , hydrocarbon or any molecule with and abstractable hydrogen atom (claim 14), which reads on,

A plasma etching composition consisting essentially of: at least one fluorocarbon, at least one additional gas selected form the group consisting of oxygen and nitrogen, and ammonia. Since Loewenstein discloses the same gaseous composition as claimed by applicants, and gas molecules collide and are in constant motion, then using Loewenstein's composition in the same manner as claimed by applicants would inherently result wherein said at least one fluorocarbon, said at least one additional gas, and said ammonia form a reactive mixture, in claim 77.

Response to Arguments

6. Applicant's arguments with respect to claims 26-29, 31, 71, and 77 have been considered but are moot in view of the new ground(s) of rejection because the Smith (US 6,277,733 B1) reference fails to address applicant's specifically claimed composition consisting essentially of: "two fluorocarbons and ammonia . . [which] form a reactive mixture," as recited in (currently amended claim 26); "CF₄, at least one other fluorocarbon and NH₃, . . . [which] form a reactive mixture," as recited in (currently amended claim 71); and "at least one fluorocarbon, at least one additional gas selected from the group consisting of oxygen and nitrogen, and ammonia . . . [which] form a reactive mixture," as recited in (currently amended claim 77). Hence, the previous rejection is withdrawn.

A modified rejection presented above addressing applicants' newly added limitations of:

"A --plasma etching-- composition consisting --essentially-- of:

--two fluorocarbon--, and ammonia, wherein said at least --two fluorocarbons--, and --said--ammonia form a reactive mixture;

CF₄, --said-- at least one other fluorocarbon, and --said-- NH₃ form a reactive mixture; and

at least one additional gas selected from the group consisting of oxygen and nitrogen, and ammonia, wherein said at least one fluorocarbon, said at least one additional gas, and said ammonia form a reactive mixture" as recited respectively in (Currently amended) Claims 26-29 and 31; 71; and 77.

7. Applicant's amendment necessitated the new ground(s) of rejection presented in

this Office action. Accordingly, THIS ACTION IS MADE FINAL. See MPEP

§ 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37

CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE

MONTHS from the mailing date of this action. In the event a first reply is filed within

TWO MONTHS of the mailing date of this final action and the advisory action is not

mailed until after the end of the THREE-MONTH shortened statutory period, then the

shortened statutory period will expire on the date the advisory action is mailed, and any

extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of

the advisory action. In no event, however, will the statutory period for reply expire later

than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Lynette T. Umez-Eronini whose telephone number is

571-272-1470. The examiner is normally unavailable on the First Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Nadine Norton can be reached on 571-272-1465. The fax phone number

for the organization where this application or proceeding is assigned is 571-273-8300.

Application/Control Number: 10/006,704

Art Unit: 1765

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Art Unit 1765

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February 6, 2006

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